Characterisation of diffraction gratings by **EUV scatterometry and GISAXS** 

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For more than 30 years, the Physikalisch-Technische Bundesanstalt has been strongly engaged in the field of metrology using synchrotron radiation. At present, at the electron storage rings BESSY II and MLS (Metrology Light Source), the activities extend over a broad range of fundamental and applied metrology in the spectral range from the far infrared to hard X-rays. EUV reflectometry and scatterometry has been developed in close cooperation with partners from industry and science for the characterization of optical elements for semiconductor lithography. In the X-ray spectral range, grazing incidence small-angle X-ray scattering (GISAXS) and Xray reflectometry (XRR) are also used to investigate structural parameters of line gratings, especially pitch, duty cycle, groove width, and line height.



# **EUV Scatterometry**



The in-vacuum Pilatus 1M detector allows for measurements at photon energies down to 1.75 keV.

3 keV

θ<sub>f</sub> / ° 0.0

0.5

1.0

lubricants used

weight: up to 50 kg

600 x 600 x 210

190 x 190 x 70 weight: up to 5 kg

no lubricants used













### Sample:

aperture

laminar grating structures produced by e-beam writing 833 nm (1200 lines/mm) pitch: land width: 292 / 250 / 208 nm etch depth: 26.57 / 30.55 / 35.55 / 41.00 nm Ru, 10 nm coating: produced by Fraunhofer IOF Fraunhofer Institut Angewandte Optik

a.u. intensity / a 10\_0.4 -0.3 -0.2 0.0 0.1 0.2 -0.10.3 0.4  $q_y$  / nm $^{-1}$ 

An intensity profile is extracted along the semi-circle. The relevant coordinate is q<sub>v</sub> because the circle shows a clipping of grating truncation rods that stretch along q<sub>z</sub> and are periodic along  $q_v$ . The power spectral density (PSD) of the Fourier amplitudes of the profile yields peaks at characteristic spacial frequencies, e.g. period, line and groove length.

higher resolution in q at fixed geometry important to determine dimensional grating parameters (period, line width, groove width) with low uncertainty

a.u. nalised PSD / a 0 0 **3**C

Set-up for diffuse scatter measurements A CCD sensor is mounted at a fix deflection angle of  $162^{\circ}$ and the sample is rocked.

grating



## Characterization of a blazed grating<sup>[2]</sup>





x-pos. of Braggsheet peak /px



Representative diffuse scatter distributions between 0. and 1. order for the blazed, holographic and e-beam grating, from left to right. The grey scale is logarithmic and the same for all three pictures (1 to 5000).



Rocking scans with the three gratings for a fix deflection angle. Data are taken with a CCD sensor and the images are stitched together.

#### References

J. Wernecke, F. Scholze, and M. Krumrey; Direct structural characterisation of line gratings with grazing incidence small-angle x-ray scattering Rev. Sci. Instrum. 83, 103906 (2012)

F. Scholze, A. Kato, J. Wernecke and M. Krumrey, EUV and X-ray scattering methods for CD and roughness measurement, Proc. SPIE 8166, 81661P (2011)

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along q<sub>2</sub>: 46.5(7) nm.

1800

1700

1600

1500

1400

1300

Linear fit of Bragg sheet maxima positions.

Blaze angle from linear fit:  $4.5(3)^{\circ}$ . Coating layer thickness

derived from diffraction corrected Bragg sheet positions

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